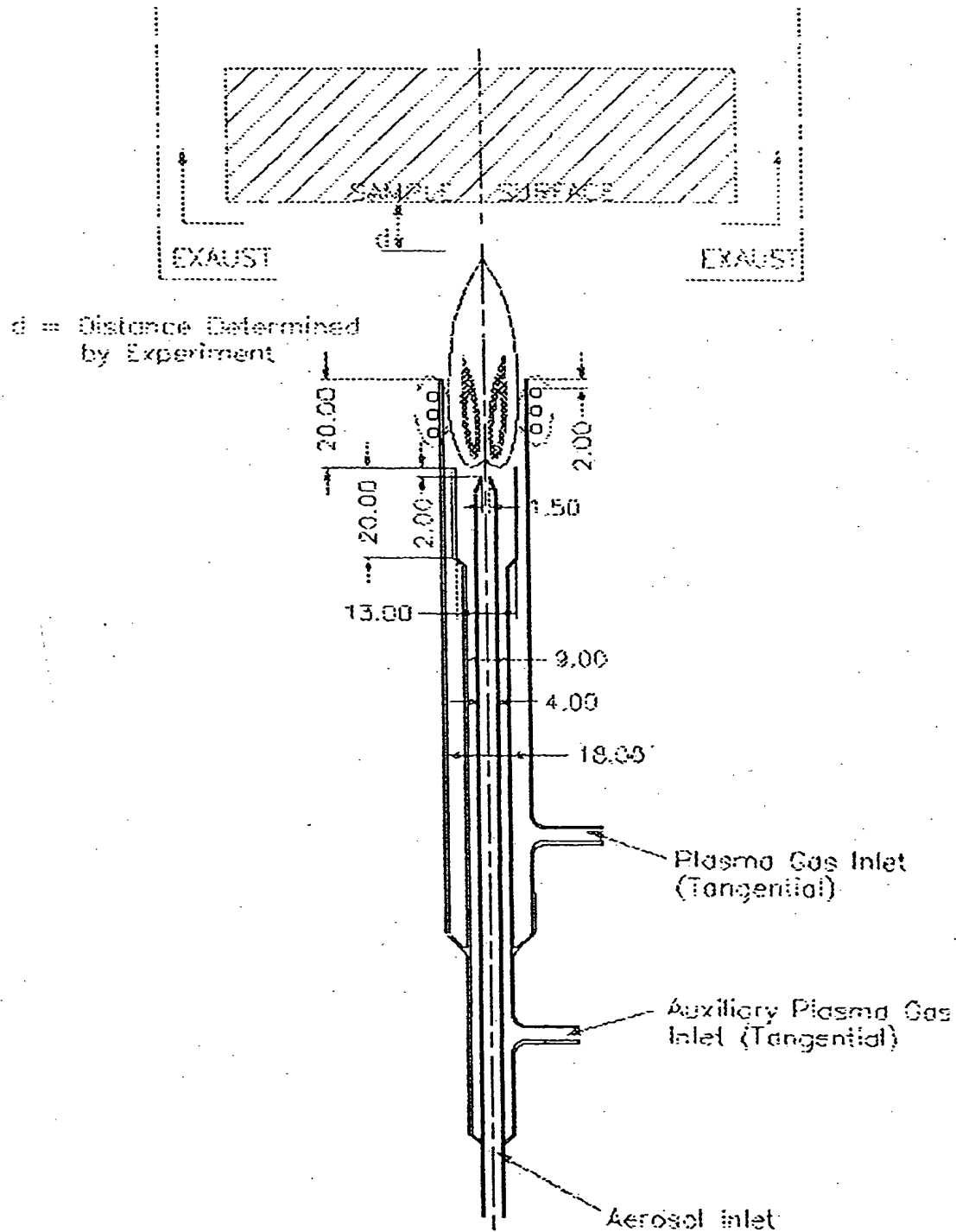
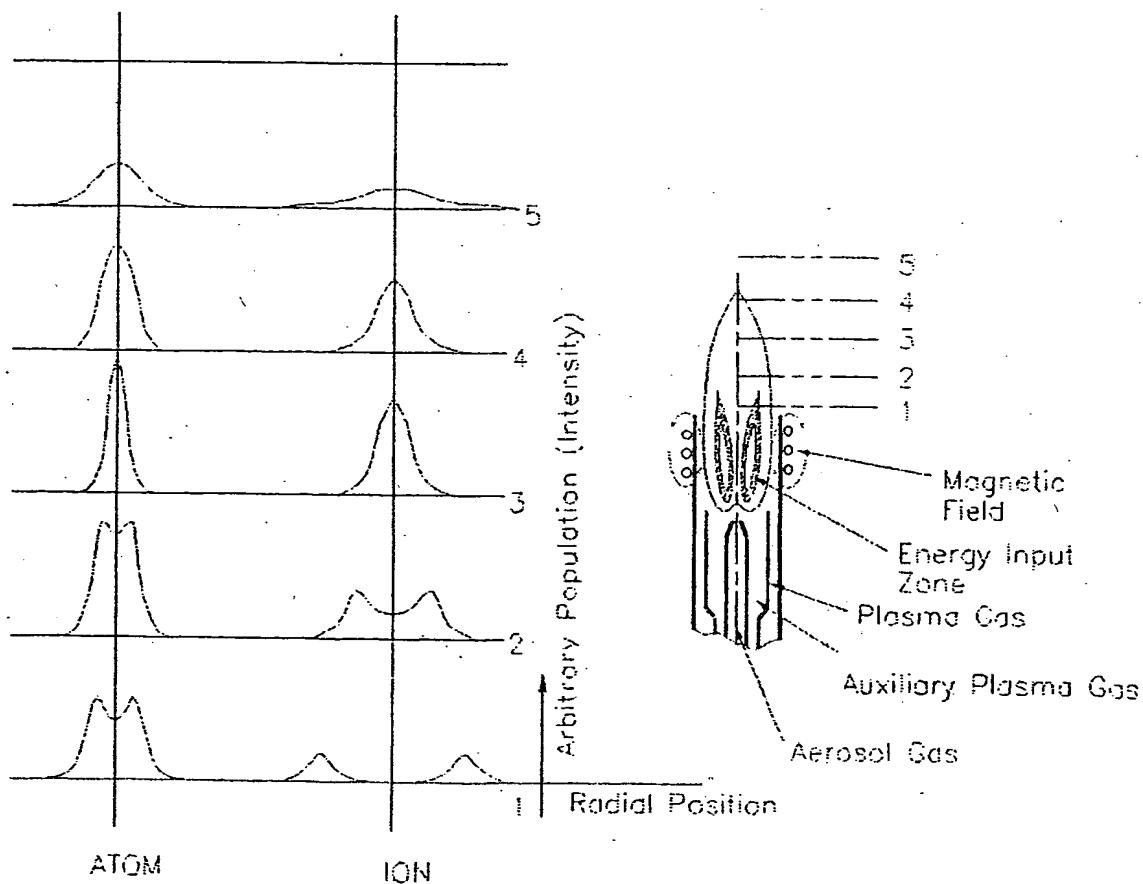


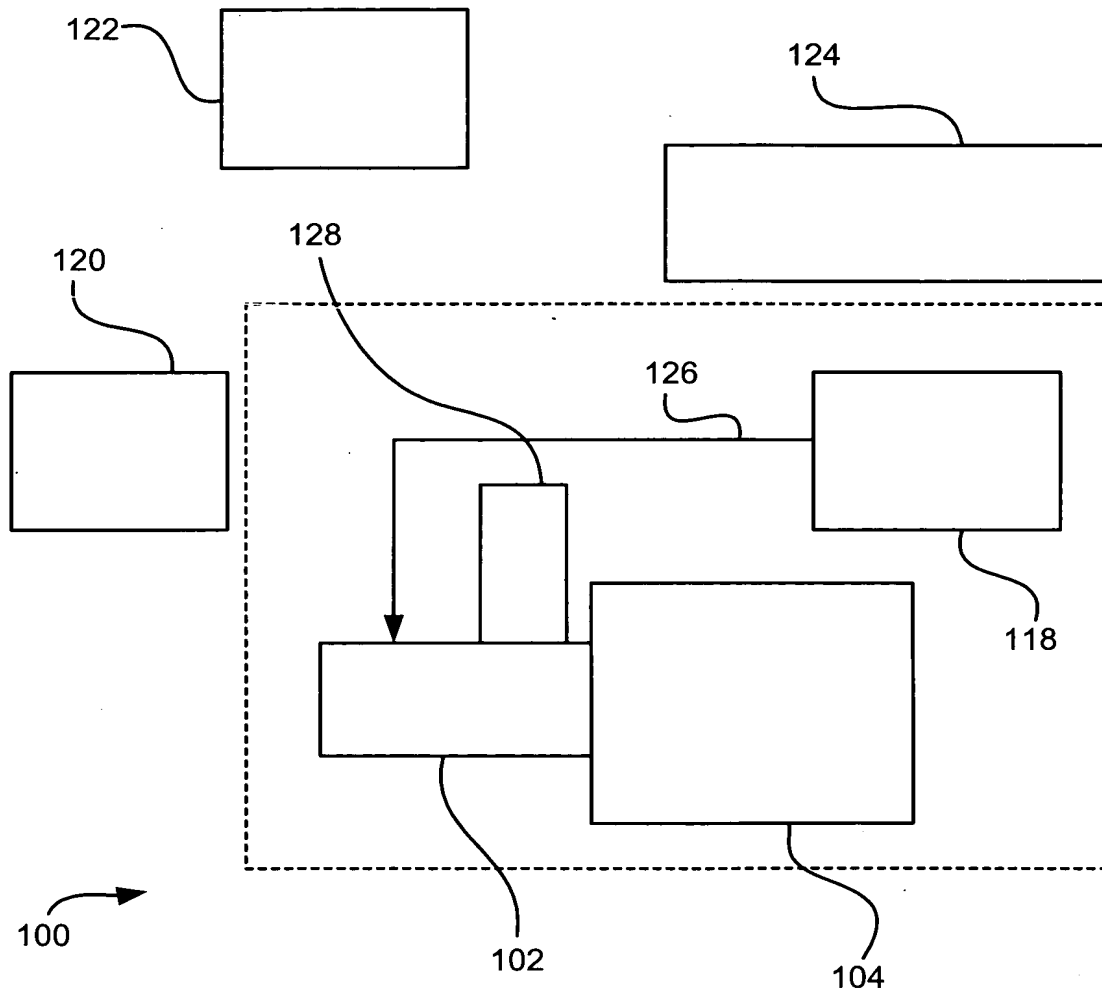
**Fig 1: ICP Torch**



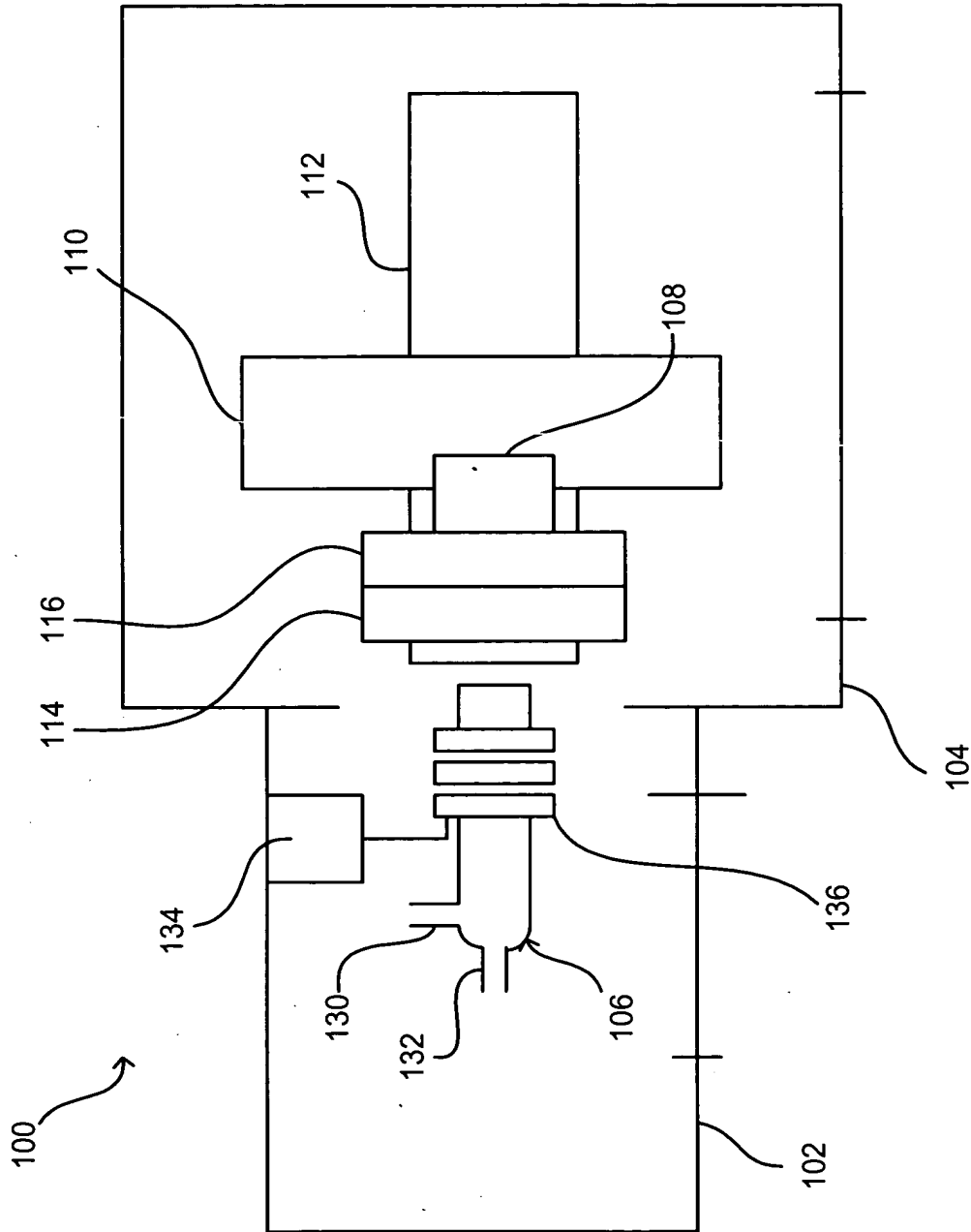
(all measurements are in millimeters)

Fig. 2: Atom and Ion Distribution in the ICP





**FIG. 3**



**FIG. 4**

THE APPARATUS AND METHOD, FOR ATMOSPHERIC PRESSURE PLASMA  
 ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES

Document No.: BEAS-01000US1

Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

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Sheet 5 of 10

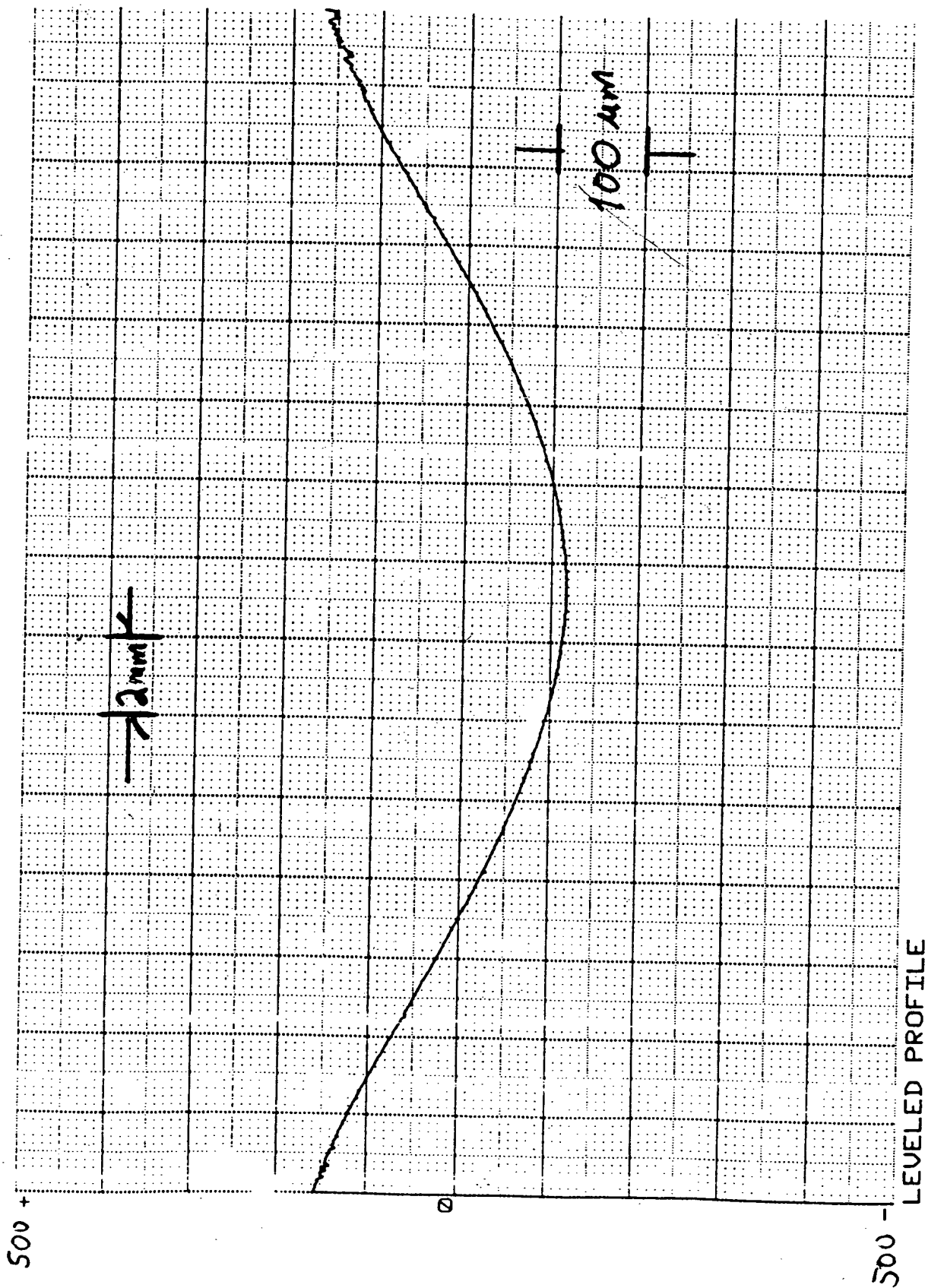


Fig 5

THE APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE REACTIVE  
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES

Docket No.: BEAS-01000US1

Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

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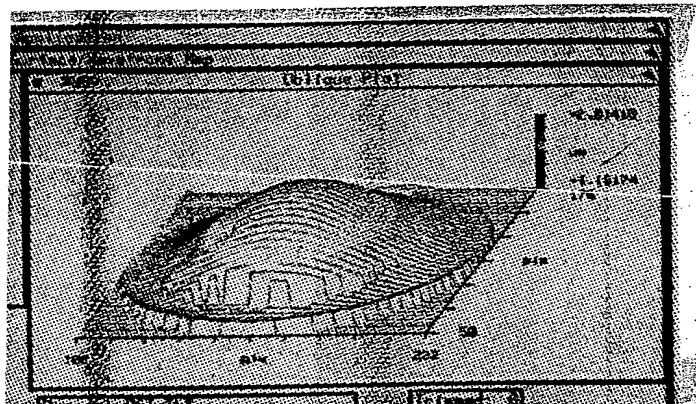
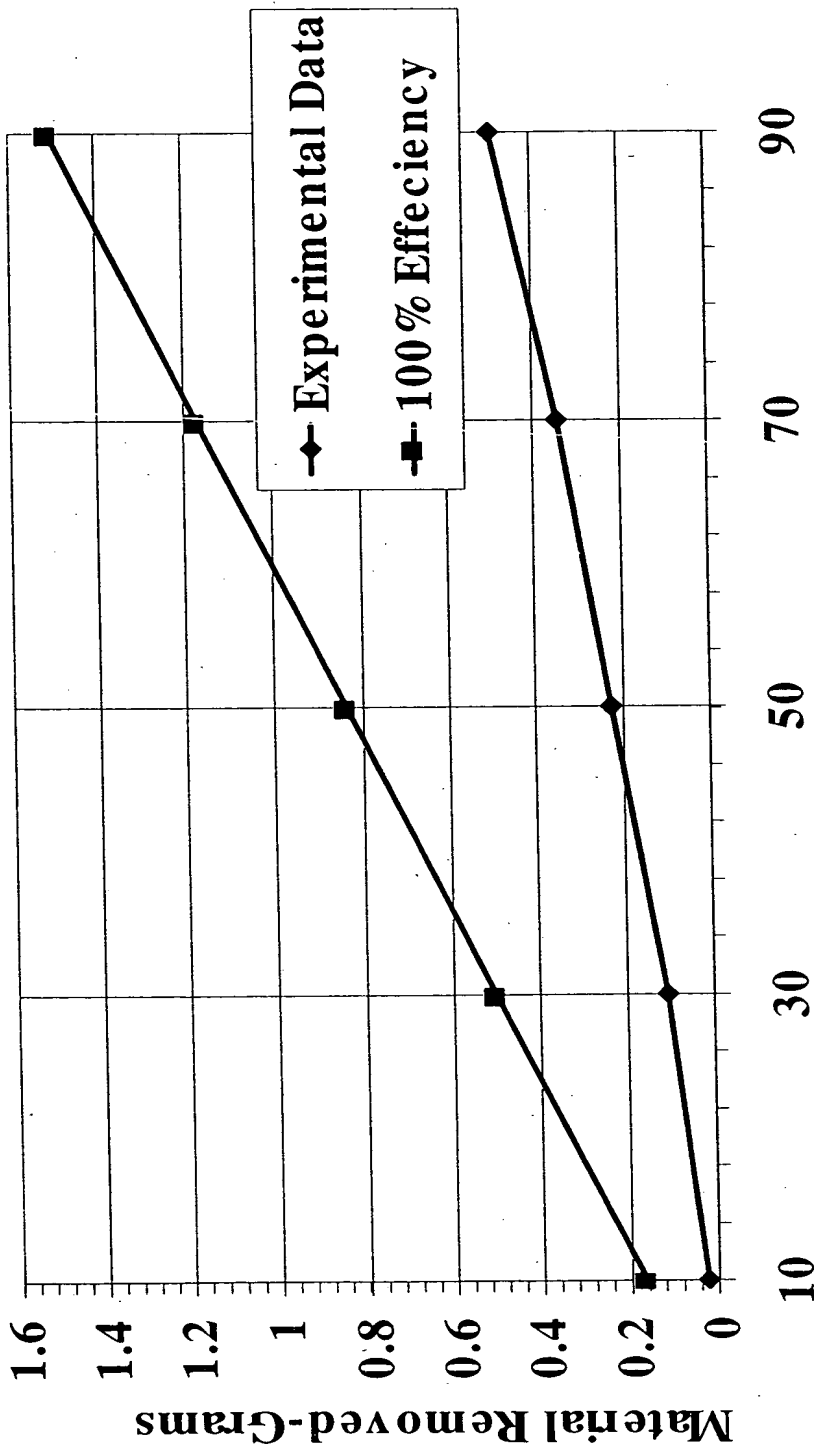


Fig. 6

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TOP SECRET

# Effect of Reaction Gas Flow Rate on Removal



Reaction Gas Concentration

Fig 7

TOP SECRET

# Effect of Distance from Plasma

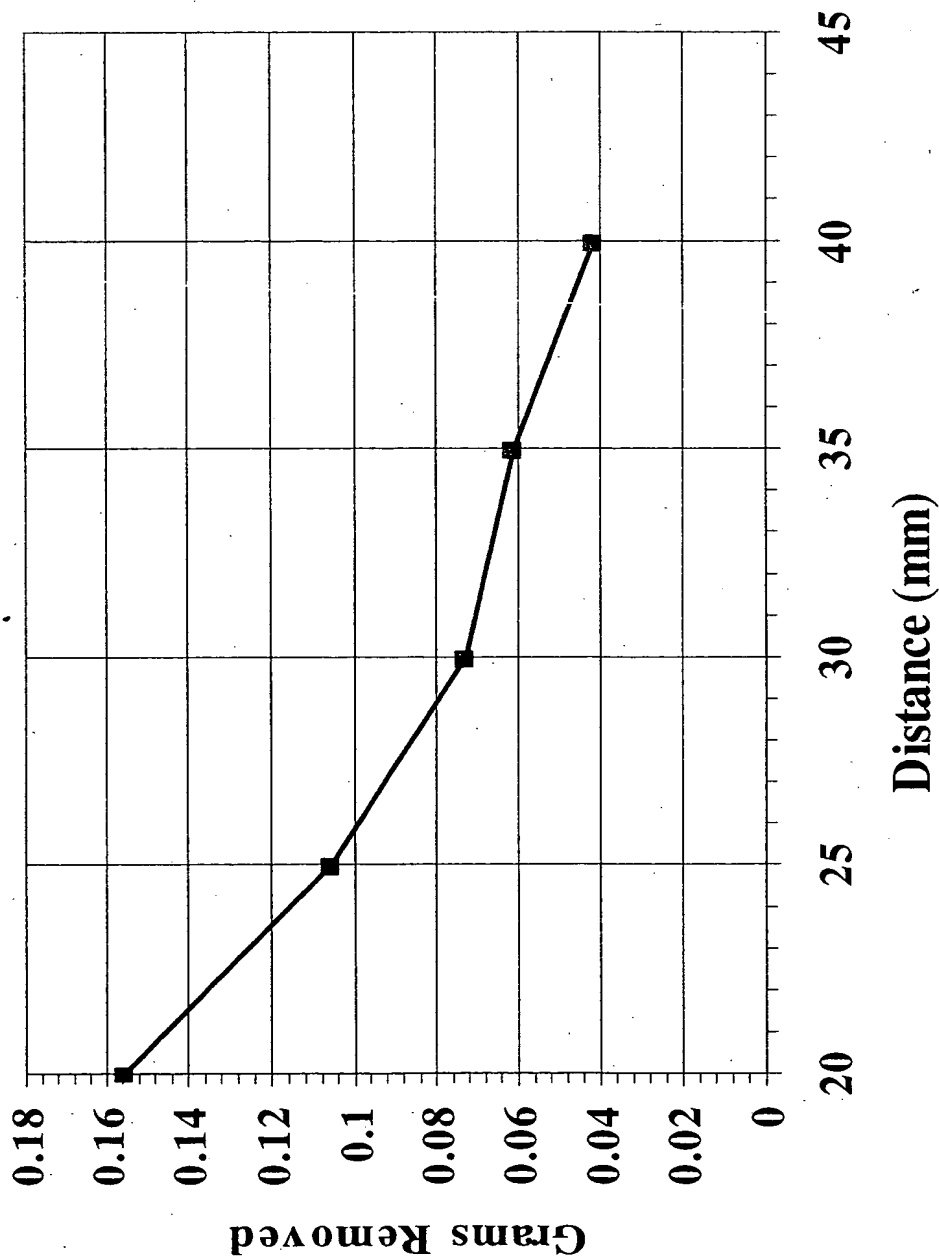


Fig 8



TOTAL SEEDOOT

## Effect of Reaction Gas Flow Rate on Efficiency

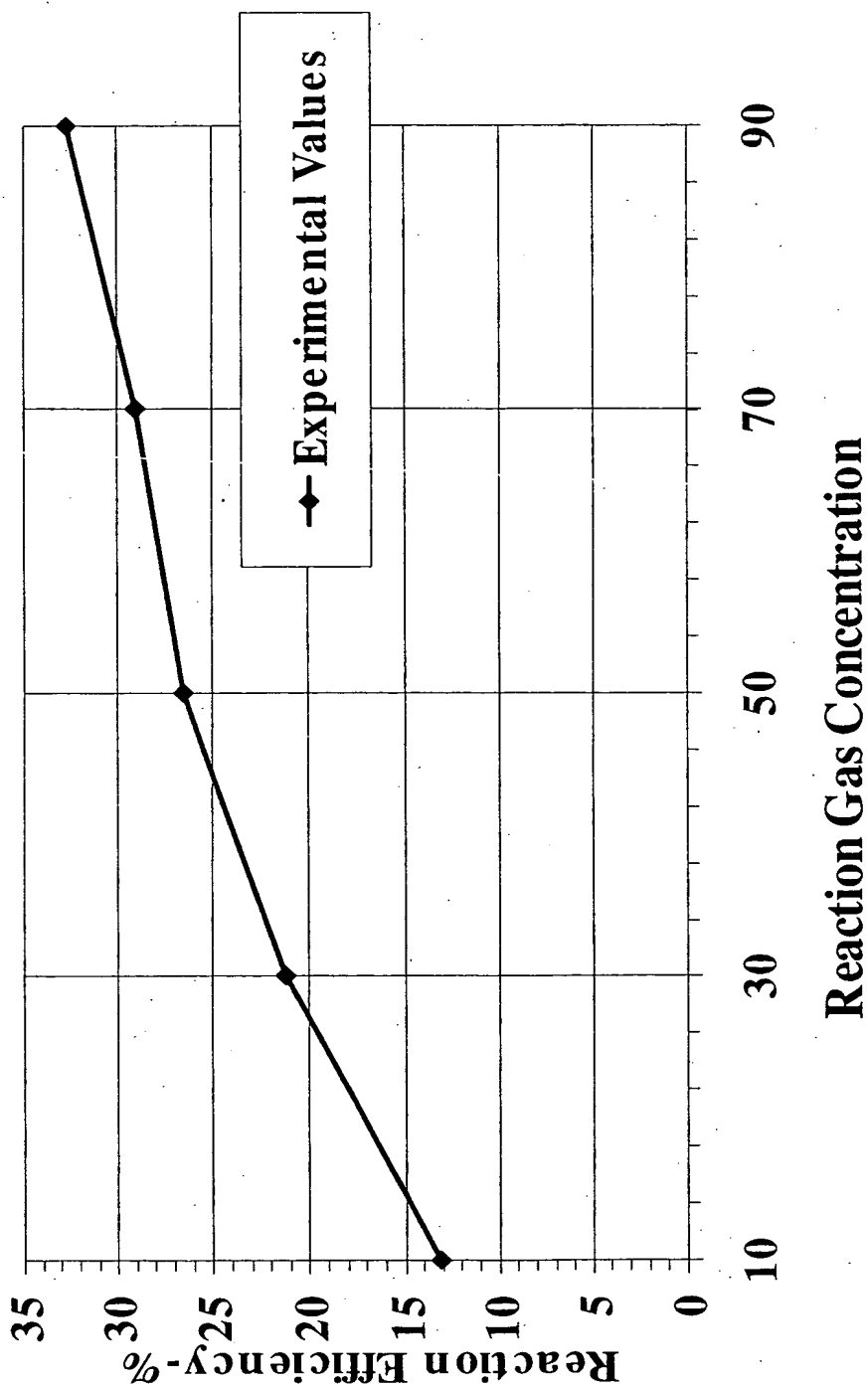


Fig 9

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## Effect of Distance from Plasma on Efficiency

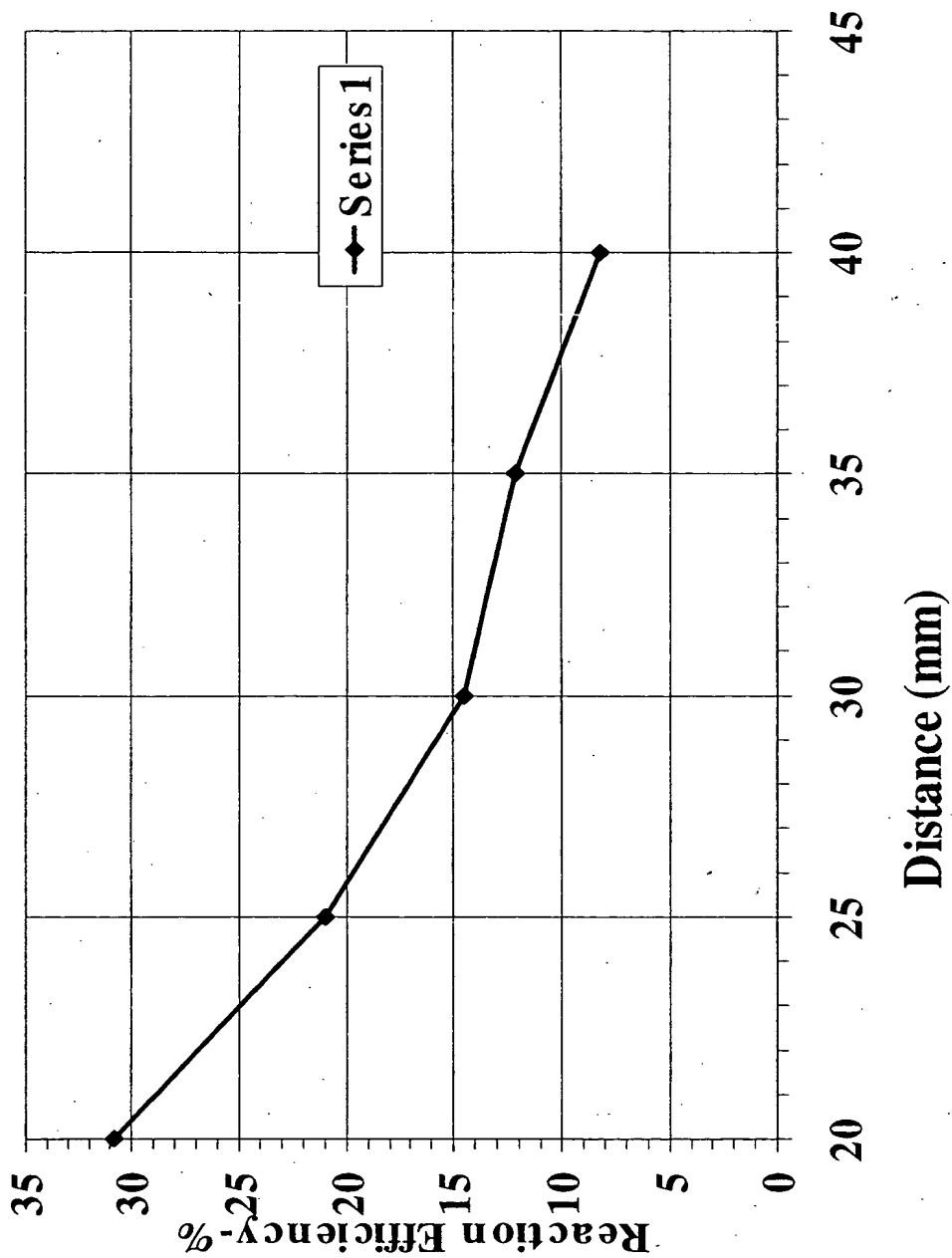


Fig 10